# Analysis of Side Band Structure in Spectral Reflectance of VUV Multilayers for Precise Determination of Period Thickness

# Tadashi Hatano\*

IMRAM, Tohoku University, 2-1-1 Katahira, Aoba-ku, Sendai 980-8577, Japan

## 1 Introduction

Multilayers are useful elements to handle VUV lights in a normal incidence geometry, where the spectral property directly depends on the layer thicknesses. Small angle X-ray diffractometry, or X-ray reflectometry is usually used for the evaluation of the period thickness of multilayers, if the substrate surface is plane. In imaging optics, however, mirrors are curved and a grazing incidence geometry is difficult to apply to that. In this report, a new analysis method of the period thickness of a normal incidence VUV multilayer mirror is presented.

## 2 Theory

A periodic stack of bilayer, material 1 and material 2, is assumed as a multilayer structure. The complex refractive indices and layer thicknesses are  $(n_1, n_2)$  and  $(d_1, d_2)$ , respectively. The period thickness and thickness ratio are defined as  $D = d_1+d_2$  and  $\gamma = d_2/D$ , respectively. Then, the Bragg's condition can be written as

$$\frac{(1-\gamma)\operatorname{Re}(\sqrt{n_1^2-\sin^2\phi})+\gamma\operatorname{Re}(\sqrt{n_2^2-\sin^2\phi})}{\lambda} = \frac{m}{2D},\qquad(1)$$

where  $\lambda$  and  $\phi$  are the wavelength and the angle of incidence, respectively. The left-hand side represents the real part of the depth component of averaged wavenumber, Re( $k_z$ ). Since the refractive indices have a  $\lambda$ -dependence, the reflectances at higher orders are usually not so high, and m = 1 is the only diffraction order to be discussed as the main peak. When the period number is N, the existence of N-1 local minima between main peaks is known. The diffraction orders for local minima can be assigned as  $m = 1 \pm 1/N$ ,  $1 \pm 2/N$ ,  $1 \pm 3/N$ , .... Relying on  $\gamma$  being not so much different from the designed value, Re( $k_z$ ) can be plotted against m. The goal is to determine D value which is given by the slop 1/2D.

### 3 Experiments and Results

A Mo/Si multilayer of N = 35,  $D \sim 7$  nm,  $\gamma = 0.41$  was deposited on a concave substrate of a 300 mm radius of curvature. The spectral reflectance was measured at  $\phi =$ 5° at BL-12A. The results are plotted in a logarithmic scale in Fig. 1. Each curve is shifted vertically by a factor of 4. Numbers in mm show the radial position of measurements. Figure 2 shows Re( $k_c$ ) at the local minima in Fig. 1 as a function of *m*. The period thickness determined from the slope is plotted in Fig. 3. The precision seems to be in a 0.1% order. The multilayer microscope of Tohoku University [1] was characterized by this method.



Fig. 1: Spectral reflectance of a Mo/Si multilayer.



Fig. 2: Real part of the depth component of averaged wavenumber at local minima in spectral reflectance.



Fig. 3: Period thickness distribution of a Mo/Si multilayer deposited on a 300<sup>*r*</sup> concave substrate.

#### <u>Reference</u>

- T. Hatano, T. Harada and M. Yamamoto, PF Act. Rep. 2007 A, **#25** (2009) 64.
- \* hatano@tagen.tohoku.ac.jp